

FORM PTO-1449 (Modified)	ATTY/DOCKET NO. FIS920010163US2	SERIAL NO. 10/757,199
LAST OF PATENTS AND PUBLICATIONS FOR APPLICANT'S INFORMATION DISCLOSURE STATEMENT		
(Use several sheets if necessary)	APPLICANT DAVID CLIFFORD LONG, ET AL.	
	FILING DATE 1/14/04	GROUP 3700

REFERENCE DESIGNATION		U.S. PATENT DOCUMENTS			CLASS	SUBCLASS	FILING DATE (IF APPRO.)
EXAMINER INITIALS	DOCUMENT NUMBER	DATE	NAME				
Og	AJ 6,160,469	12/12/00	Liberatore et al.				
Og	AK 6,189,200	02/20/01	Takeuchi et al.				
Og	6,459,352	10/01/02	Liu, et al.				
Og	5,884,990	3/23/99	Burghartz, et al.				
Og	6,292,086	9/18/01	Chu				

FOREIGN PATENT DOCUMENTS						
	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION
						YES NO

OTHER ART (Including Author, Title, Date, Pertinent Pages, etc.)	

EXAMINER	DATE CONSIDERED
C.J. Arbes	4/1/05

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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REFERENCE DESIGNATION		U.S. PATENT DOCUMENTS				
EXAMINER INITIALS	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE (IF APPRO.)
CPA	AA 3,812,442	05/21/74	Muckelroy			
CPA	AB 5,389,428	02/14/95	Fleming et al.			
CPA	AC 5,610,569	03/11/97	Hwang et al.			
CPA	AD 5,945,902	08/31/99	Lipkes et al.			
CPA	AE 6,008,102	12/28/99	Alford et al.			
CPA	AF 6,008,151	12/28/99	Sasaki et al.			
CPA	AG 6,104,272	08/15/00	Yamamoto et al.			
CPA	AH 6,147,573	11/14/00	Kumagai et al.			

FOREIGN PATENT DOCUMENTS

	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION
						YES
						NO

OTHER ART (Including Author, Title, Date, Pertinent Pages, etc.)

CPA	AI IBM Technical Disclosure Bulletin, Vol. 29, No. 2, July 1986 entitled, "Method Of Fabricating Deflection Coils For Electron Lithography Systems"
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